



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 7353**  
Tetsuji TOGAWA et al. : Attorney Docket No. 2005\_1890A  
Serial No. 10/559,135 : Group Art Unit 3723  
Filed February 11, 2008 : Examiner Eileen P. Morgan  
SUBSTRATE POLISHING  
APPARATUS AND SUBSTRATE  
POLISHING METHOD : **Mail Stop: Amendment**

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**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

Sir:

In response to the Office Action of November 12, 2008, the period for response having been extended by one month to March 12, 2009, please amend the above-identified U.S. Patent application as follows.